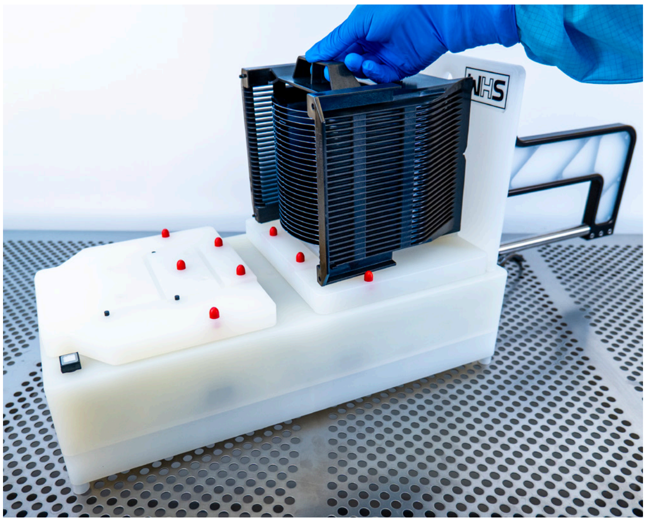
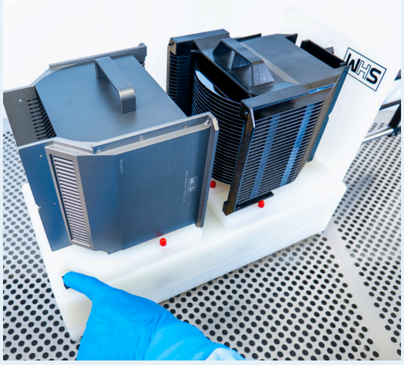
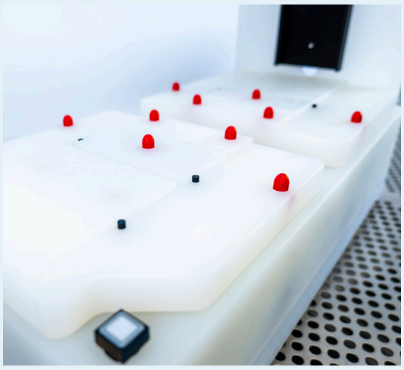
AUTOMATIC WAFER EXCHANGE SYSTEM



The WHS-T5 series is a precision-engineered, automatic wafer exchange system. This design differs in automation from the WHS-T2 series: before the transfer takes place the receiving cassette is automatically moved towards the sent cassette. Designed for an even more safe moving of wafers between two SEMI-compliant cassettes. No risk of touching wafers when placing or taking away a cassette. Specially when a low-profile cassette is involved. The WHS-T5 is compatible with high- and low-profile plastic process cassettes, metal cassettes, and most shipping cassettes with an H-BAR. This advanced system ensures smooth and efficient wafer transfers across various semiconductor applications, including shipping/receiving, epitaxial, wet chemistry, and thermal processing areas.





The WHS-T5 is equipped with one-button for the exchange when integrated SEND and RECEIVE stage cassette-in-place sensors are activated. An adjustable transfer arm resistance sensor to detect excessive forces during motion—safeguarding wafer integrity.

Additionally, an ultrasonic sensor provides an extra safety check by detecting if wafers are already present in the RECEIVE cassette when the operator initiates a transfer, further preventing potential errors or wafer damage.

Constructed from antistatic, chemical-resistant materials, the WHS-T5 guarantees a clean, controlled environment, meeting ISO 4 (FS209E Class 10) cleanroom standards. Its versatility makes it suitable for wafer handling in metrology, etch, inspection, probe, and test areas.

FEATURES AND ADVANTAGES

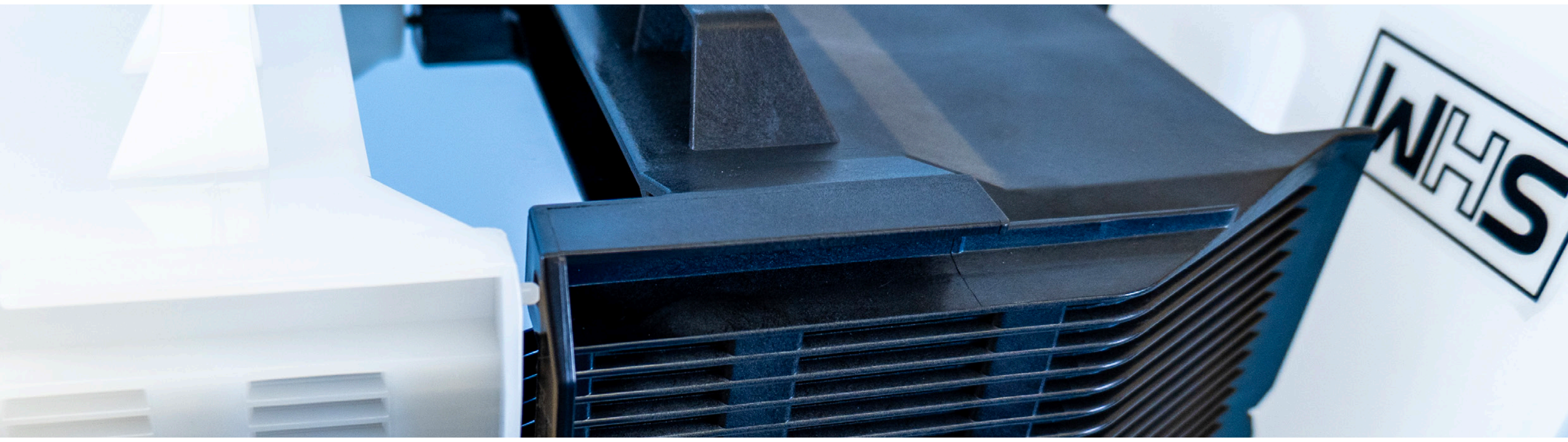
- Automatic exchange between SEMI-compliant cassettes
- Easy one-button operation
- Equipped with integrated safety sensors
- Antistatic, chemical-resistant materials for cleanroom use
- ISO 4 and CE-certified

Manufactured in an ISO9001 certified facility and CE certified, the WHS-T5 offers a robust, reliable solution for precision wafer transfers in semiconductor manufacturing environments.

AUTOMATIC WAFER EXCHANGE SYSTEM

ITEM	SPECIFICATIONS
Wafer size	150 mm & 200 mm
Materials, transfer arm	Antistatic Polyoxymethylene
Materials, stage	Natural Polypropylene
Materials, guides	Antistatic Polyoxymethylene
Cleanliness	ISO 4 (FS209E Class 10)

*** NOTE: Please specify cassette model number(s) when ordering ***



ORDERING INFORMATION

WHS-T5 – 601

CODE	MODEL
601	Automatic wafer exchange system, automatic, 150 mm (6”)
801	Automatic wafer exchange system, automatic, 200 mm (8”)

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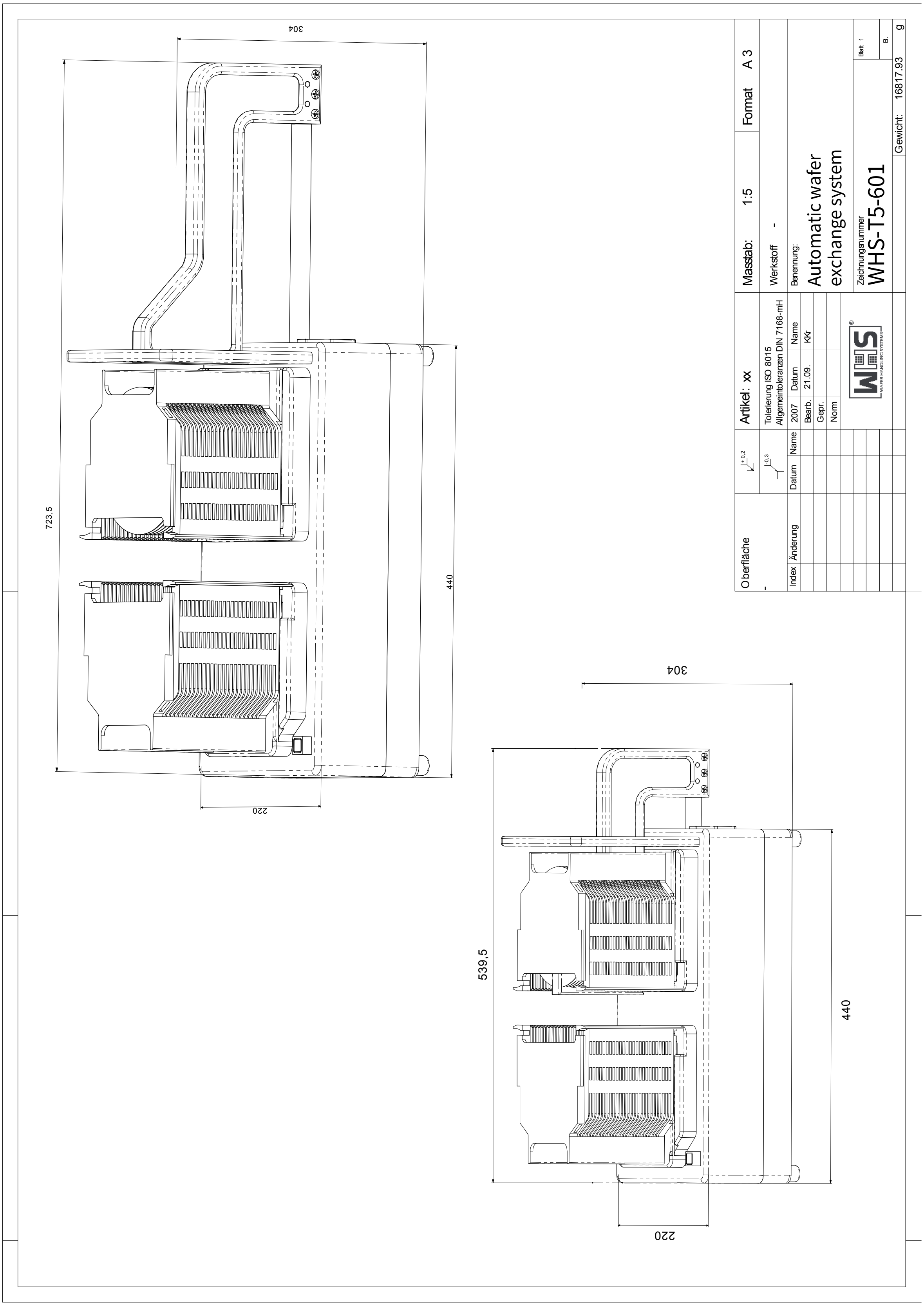
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220
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539,5
440
220
Oberfläche
-
Artikel: xx
Tolerierung ISO 8015
Allgemeintoleranzen DIN 7168-mH
Masstab: 1:5
Format A 3
Werkstoff -
Benennung:
Automatic wafer exchange system
Zeichnungsnummer
WHS-T5-601
Gewicht: 16817.93 g
Blatt 1
B.
Index
Änderung
Datum
Name
2007
Datum
Name
Bearb.
21.09.
KK
Gepr.
Norm
WHS WAFER HANDLING SYSTEMS

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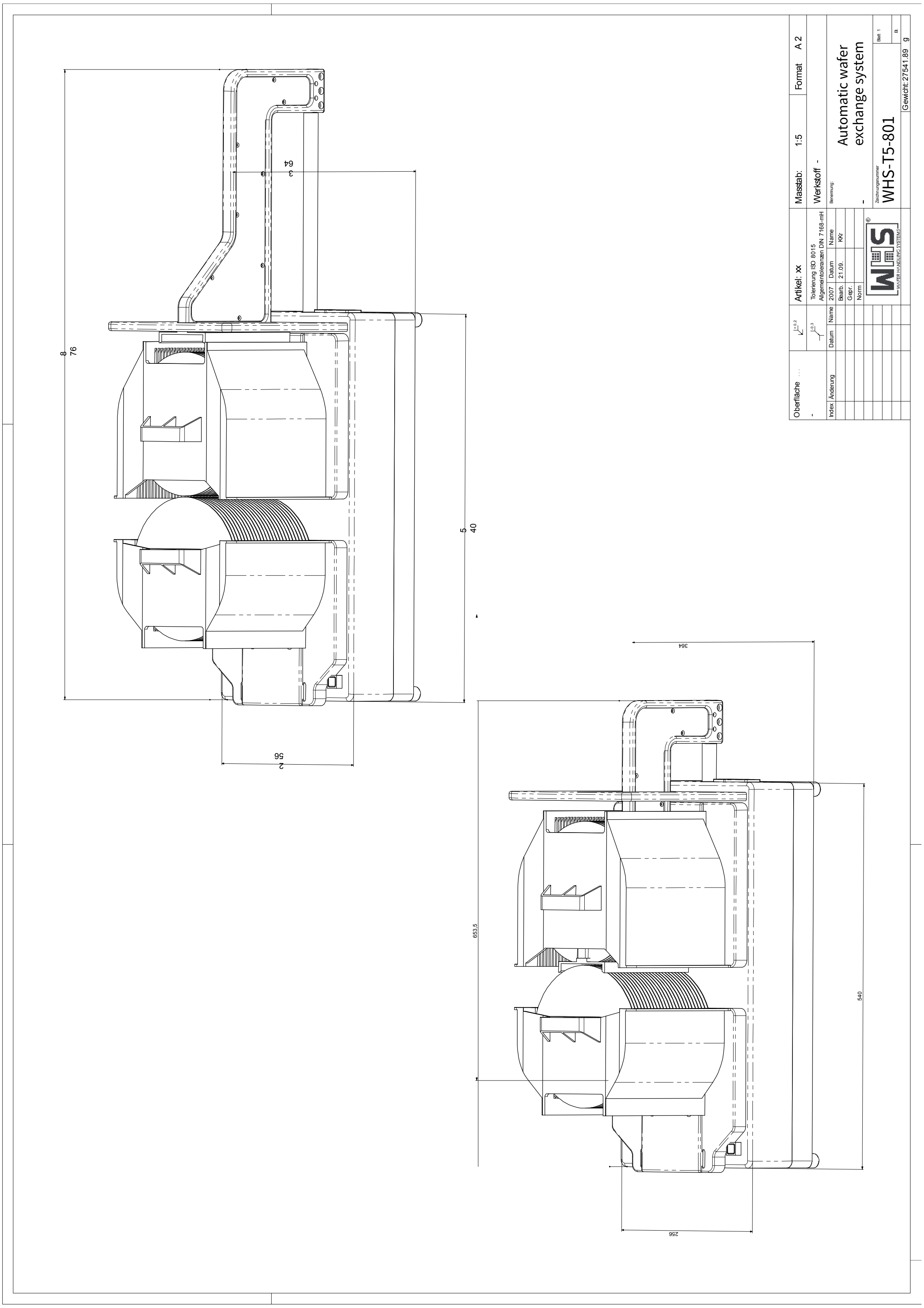
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Oberfläche
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Masstab: 1:5
Format A 2
Tolerierung ISO 8015
Allgemeintoleranzen DIN 7168-mH
Werkstoff -
Index
Änderung
Datum
Name
2007
Bearb.
21.09.
KKr
Gepr.
Norm
Benennung:
Automatic wafer exchange system
Zeichnungsnummer
WHS-T5-801
Blatt 1
Bl.
Gewicht: 27541.89 g